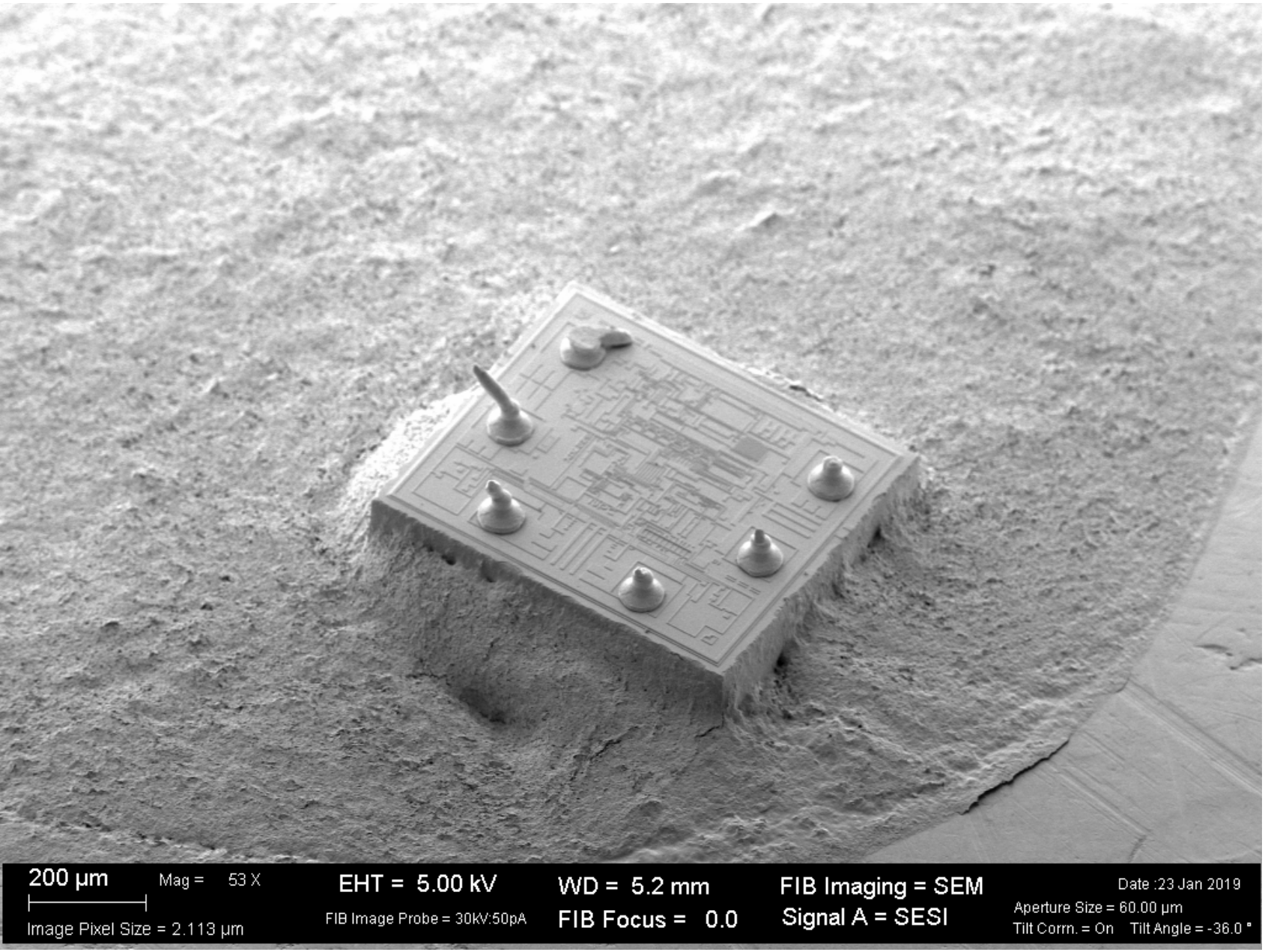
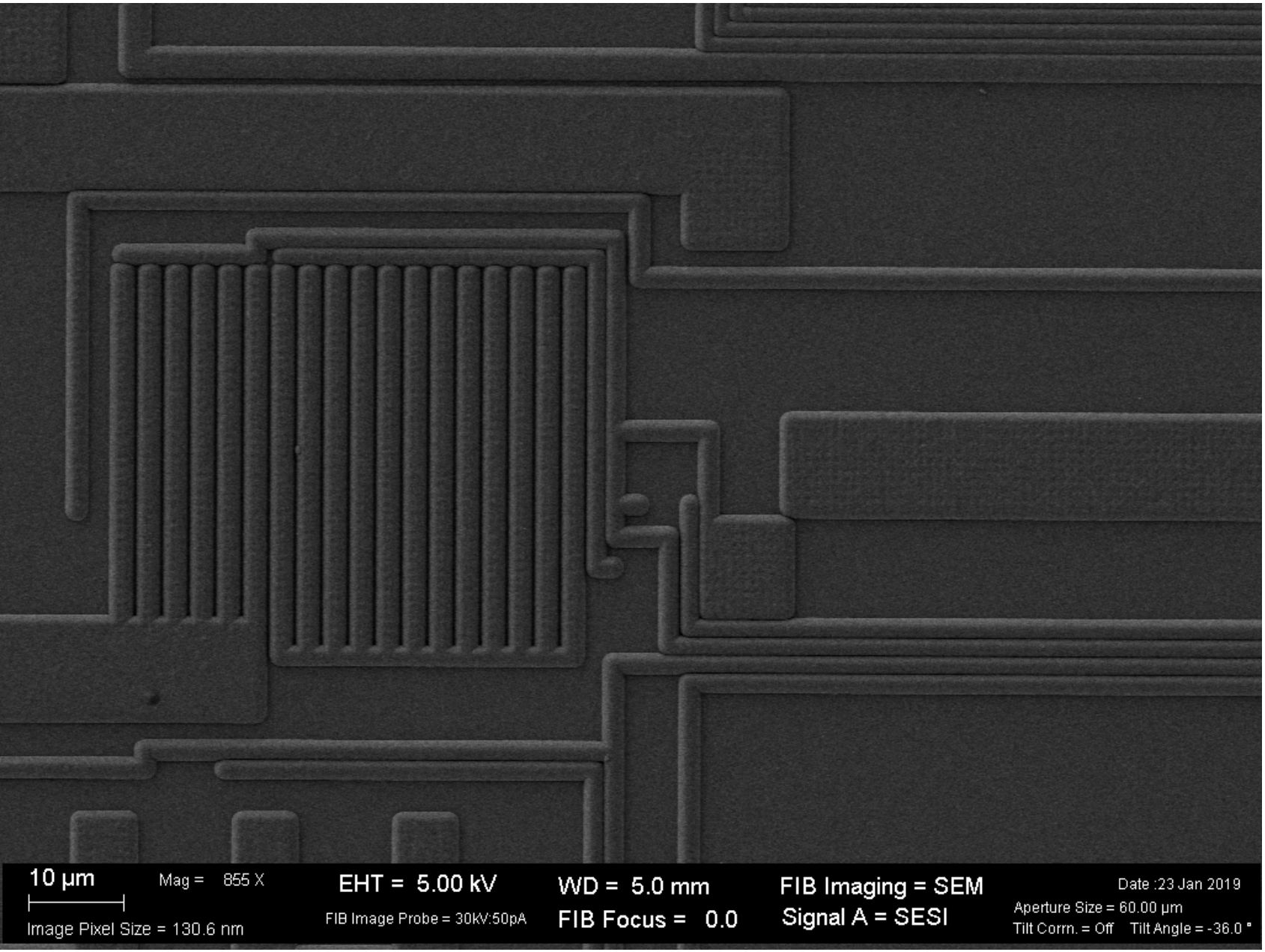
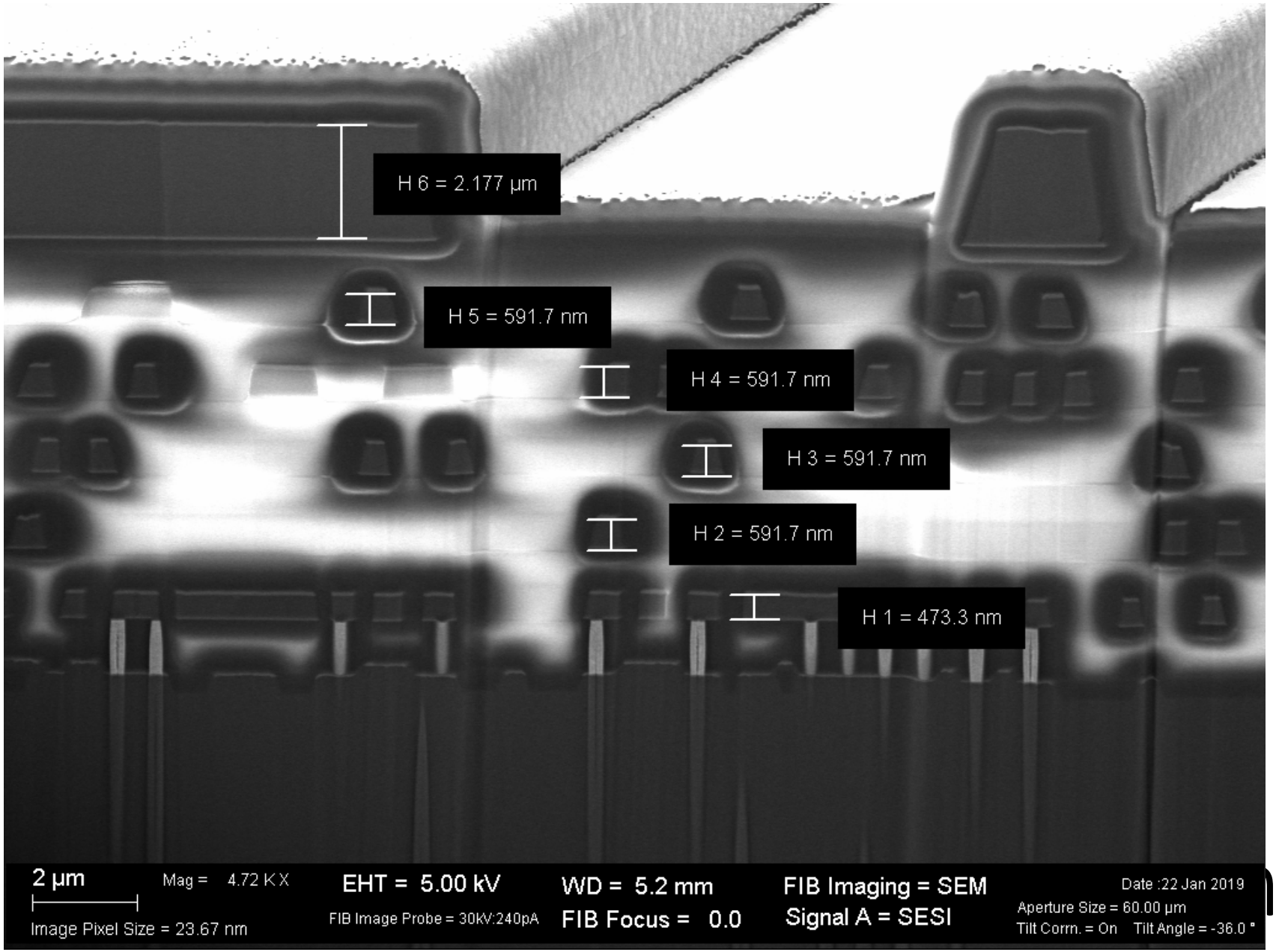
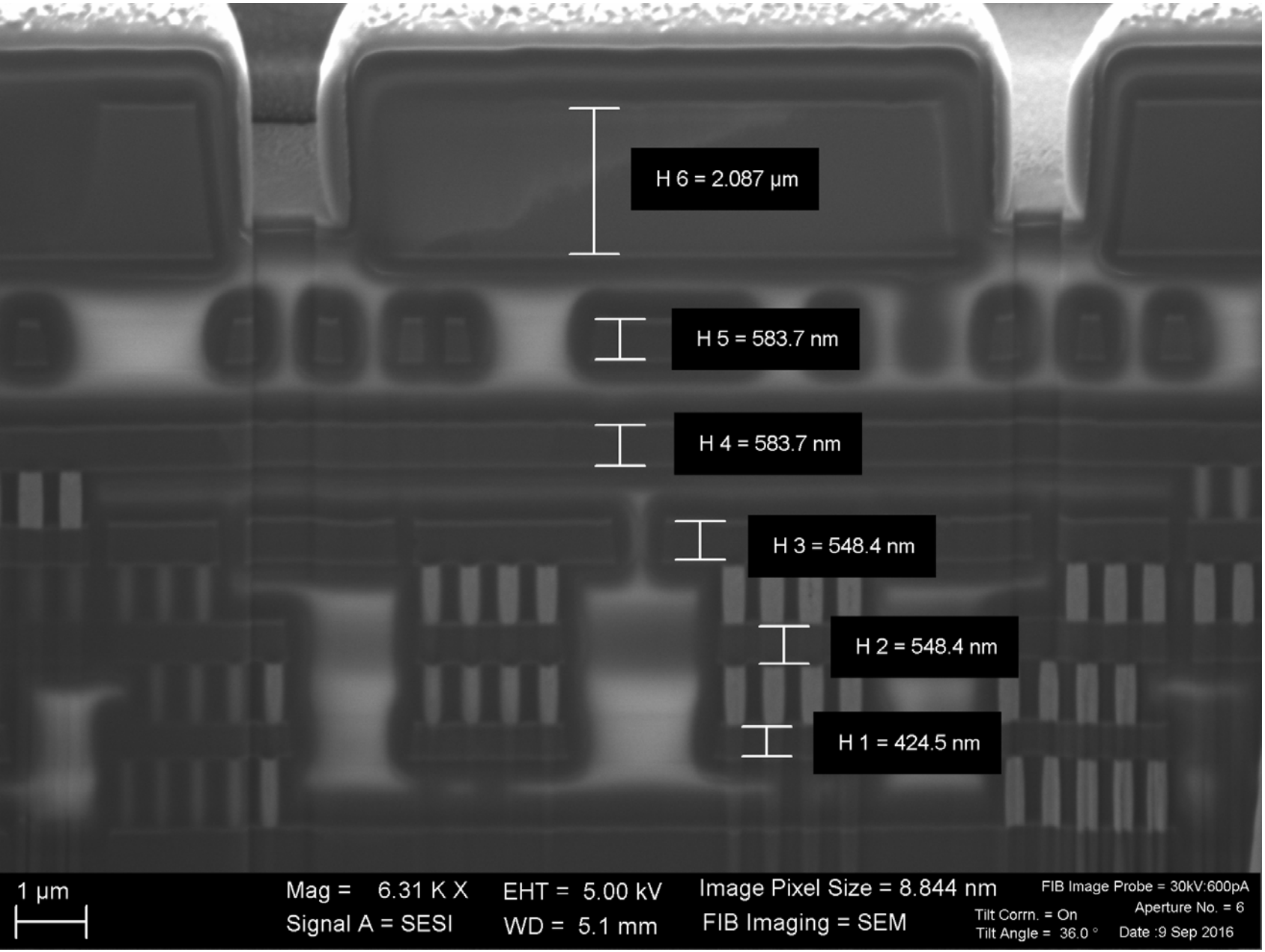

200 µm
Mag = 53 X
Image Pixel Size = 2.113 µm
EHT = 5.00 kV
FIB Image Probe = 30kV:50pA
WD = 5.2 mm
FIB Focus = 0.0
FIB Imaging = SEM
Signal A = SESI
Date :23 Jan 2019
Aperture Size = 60.00 µm
Tilt Corrn. = On
Tilt Angle = -36.0 °

Chip

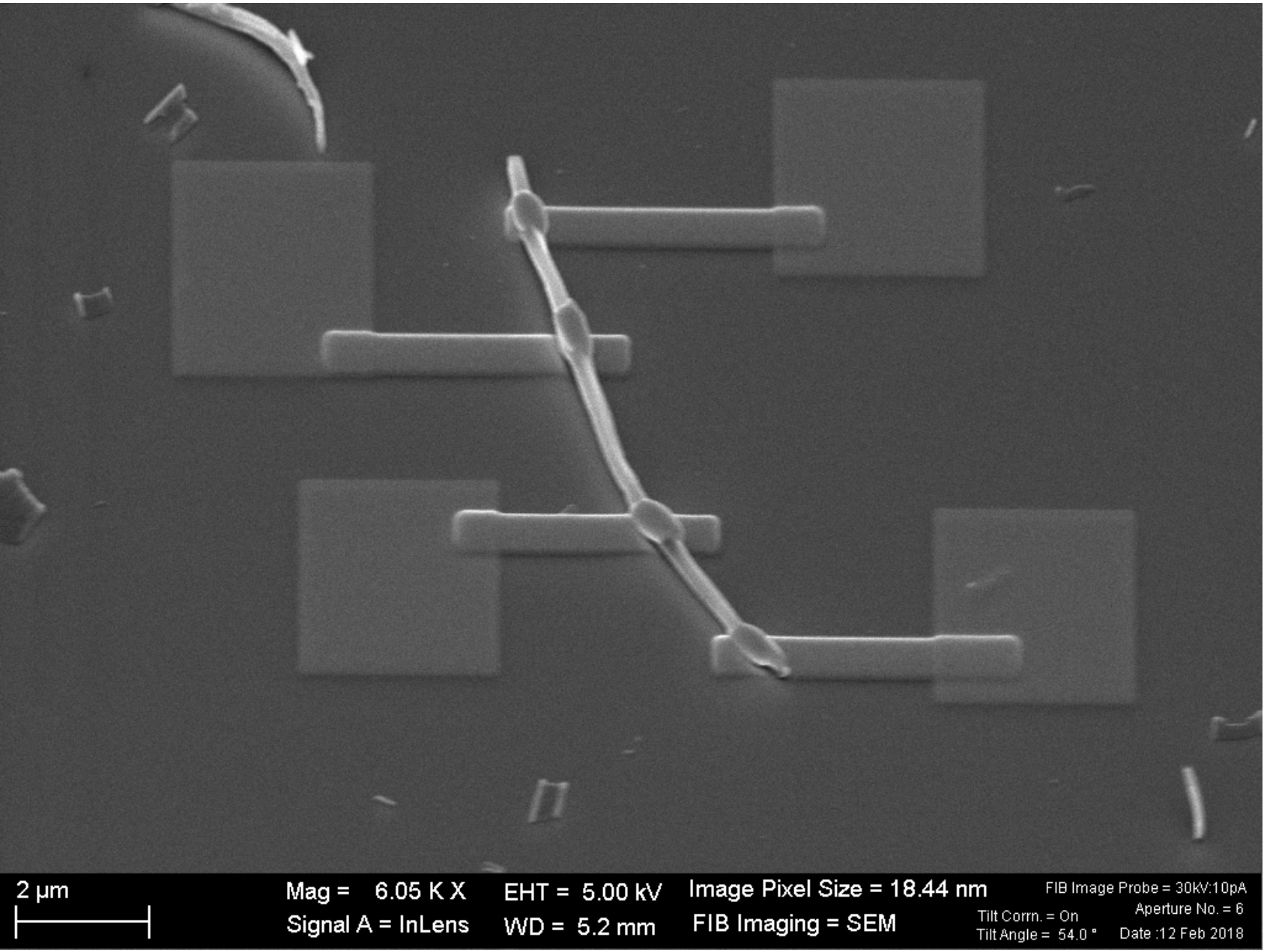

10 µm
Mag = 855 X
Image Pixel Size = 130.6 nm
EHT = 5.00 kV
FIB Image Probe = 30kV:50pA
WD = 5.0 mm
FIB Focus = 0.0
FIB Imaging = SEM
Signal A = SESI
Date :23 Jan 2019
Aperture Size = 60.00 µm
Tilt Corrn. = Off
Tilt Angle = -36.0 °

Chip

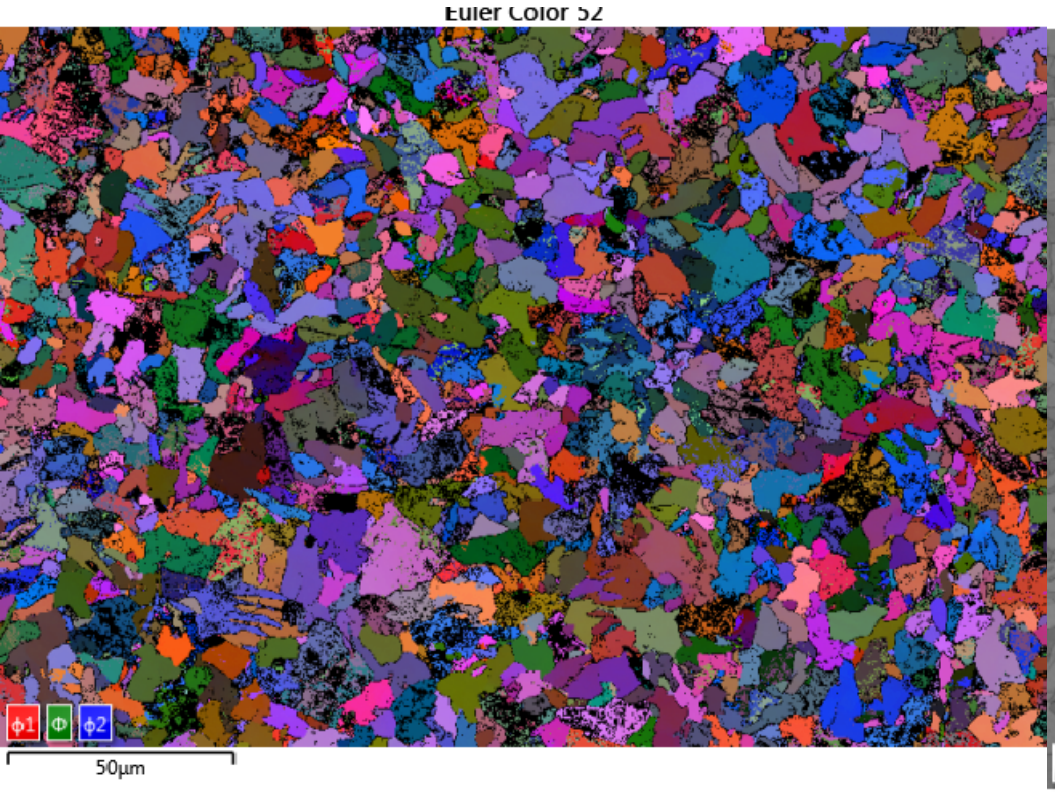

H 6 = 2.177 µm
H 5 = 591.7 nm
H 4 = 591.7 nm
H 3 = 591.7 nm
H 2 = 591.7 nm
H 1 = 473.3 nm
2 µm
Mag = 4.72 K X
Image Pixel Size = 23.67 nm
EHT = 5.00 kV
FIB Image Probe = 30KV:240pA
WD = 5.2 mm
FIB Focus = 0.0
FIB Imaging = SEM
Signal A = SESI
Date :22 Jan 2019
Aperture Size = 60.00 µm
Tilt Corrn. = On
Tilt Angle = -36.0 °

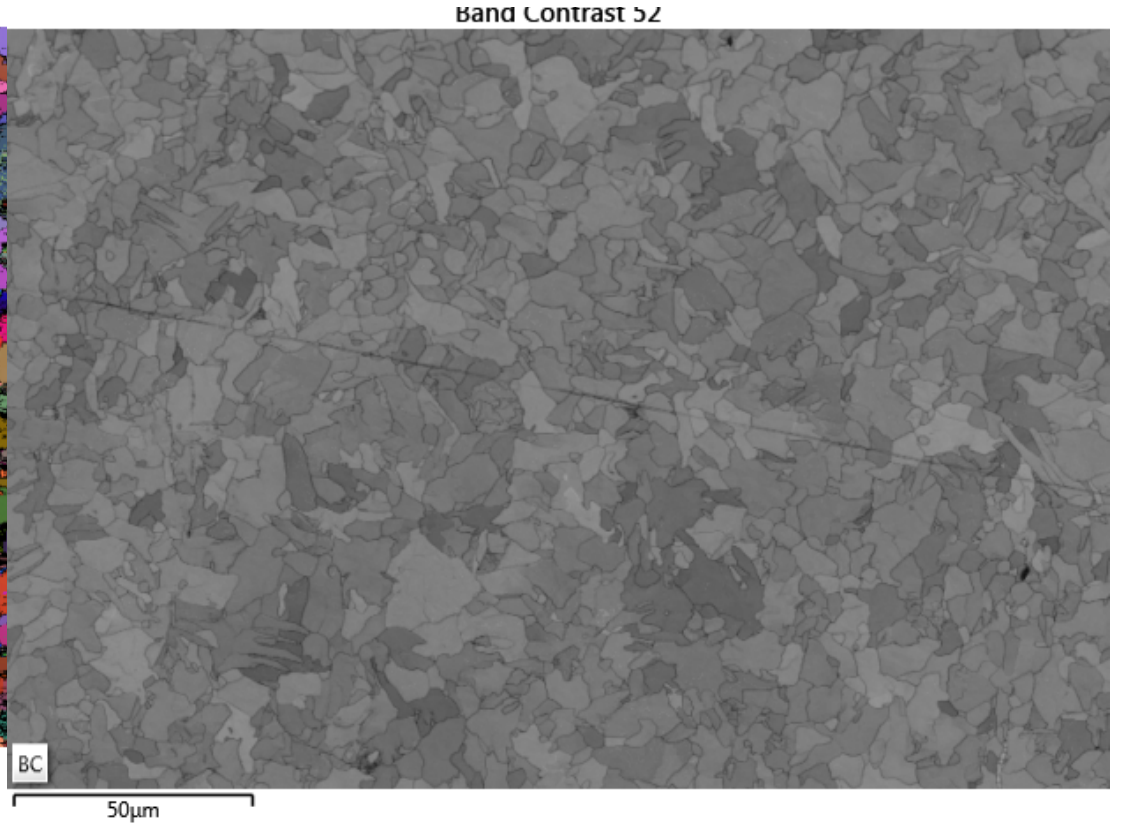

H 6 = 2.087 µm
H 5 = 583.7 nm
H 4 = 583.7 nm
H 3 = 548.4 nm
H 2 = 548.4 nm
H 1 = 424.5 nm
1 µm
Mag = 6.31 K X
Signal A = SESI
EHT = 5.00 kV
WD = 5.1 mm
Image Pixel Size = 8.844 nm
FIB Imaging = SEM
Tilt Corrn. = On
Tilt Angle = 36.0 °
FIB Image Probe = 30kV:600pA
Aperture No. = 6
Date :9 Sep 2016

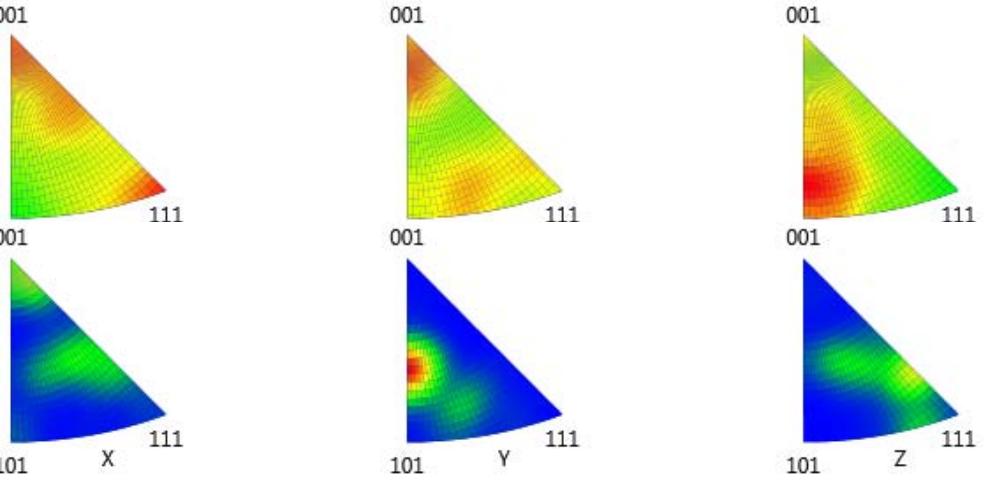
Chip

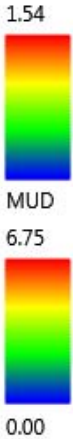


Medidas eléctricas en 4 puntos


Euler Color 52
ϕ1
Φ
ϕ2
50µm

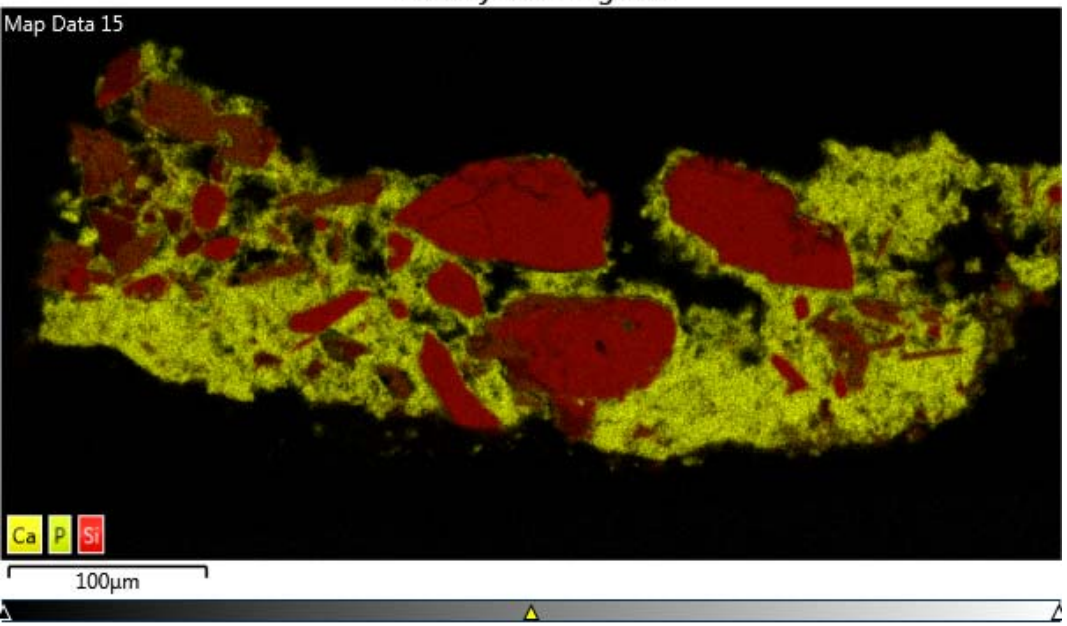

Band Contrast 52
BC
50µm


001
111
001
X
001
111
001
Y
001
111
001
Z

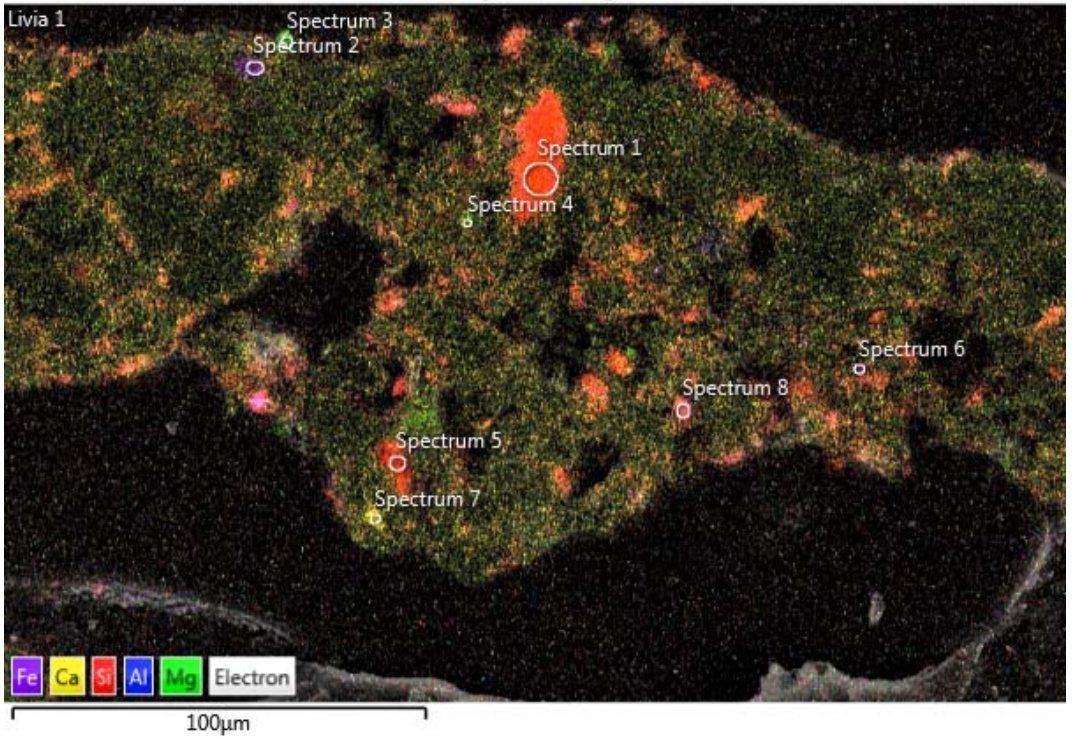

1.54
MUD
6.75
0.00

EBSD Acero

EDS Layered Image 15



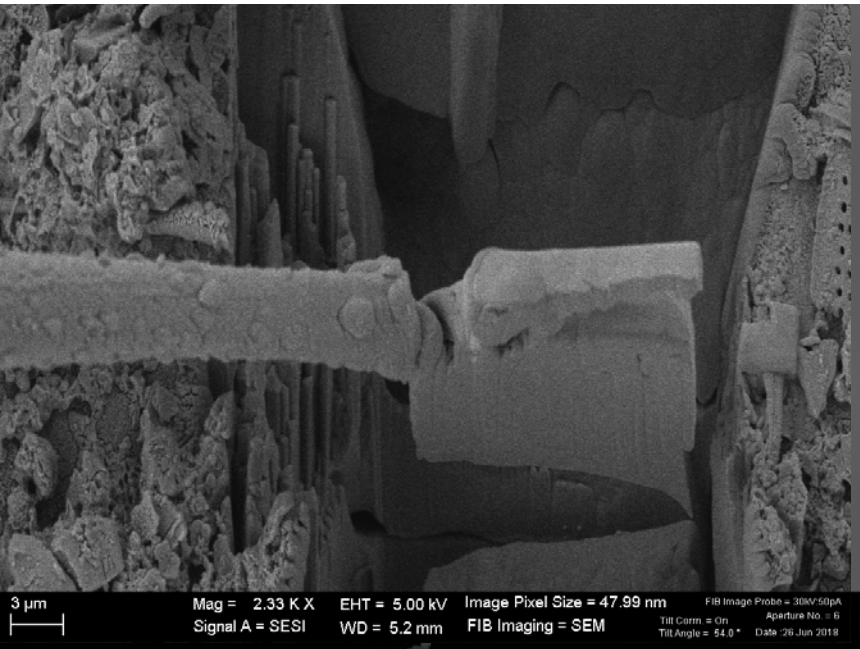
EDS Layered Image 12

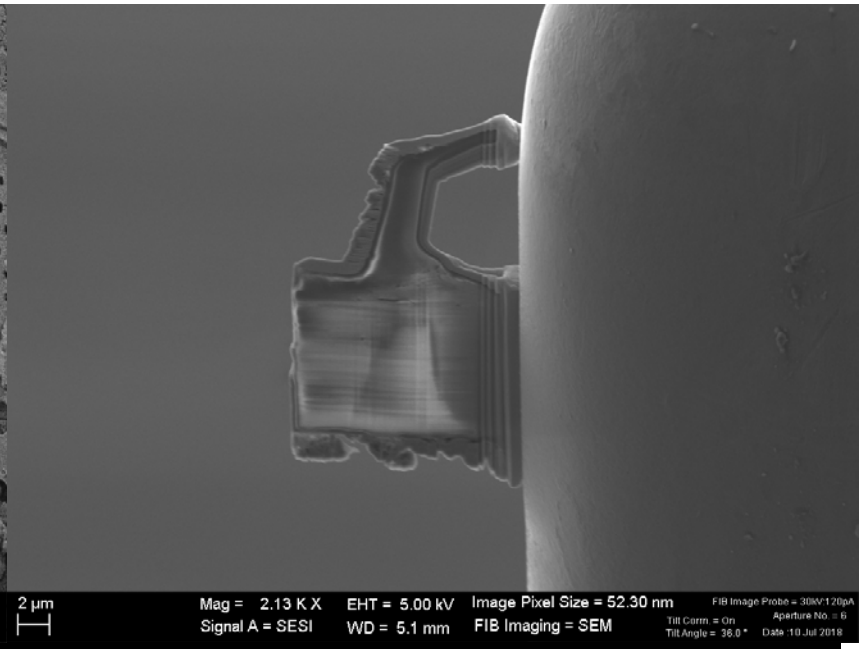


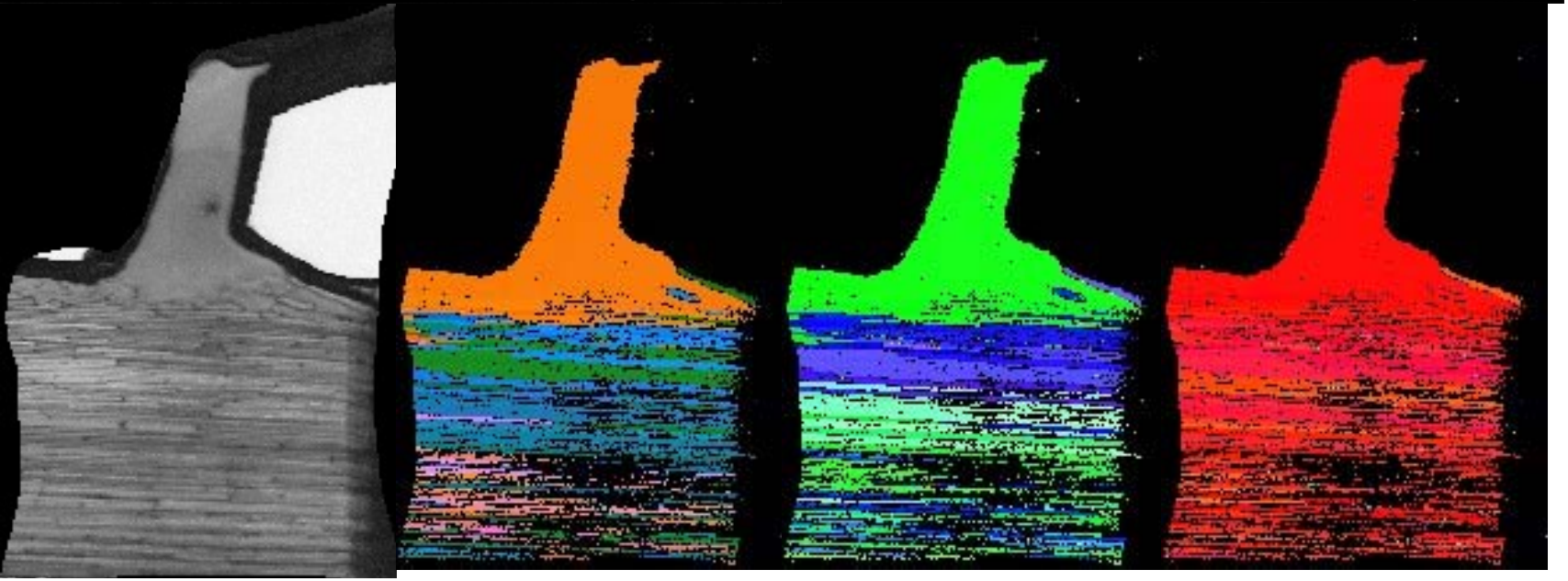
EDS pigmentos


UNIVERSIDAD DE SEVILLA
Mag = 2.33 K X
1 µm
WD = 5.2 mm
EHT = 5.00 kV
Signal A = SESI
ESB Grid = 1500 V
Date :18 Feb 2015 Time :12:49:56
Auriga-45-75
FIB Imaging = SEM
Noise Reduction = Pixel Avg.
FIB Probe = 30kV:50pA
System Vacuum = 2.16e-006 mbar

logo







TKD

Catillopecten